

ACKNOWLEDGEMENT RECEIPT

Electronic Version 1.1

Stylesheet Version v1.1.1

Title of Invention

HIGH PRESSURE PROCESSING CHAMBER FOR A SEMICONDUCTOR WAFER

Submission Type : Information Disclosure
Statement

Application Number:

10/680783



EFS ID:

107799

Server Response:

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ISVR1	Submission was successfully submitted - Even if Informational or Warning Messages appear below, please do not resubmit this application
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First Named Applicant: William Jones

Attorney Docket Number:

Timestamp: 2006-07-12 17:34:57 EDT

From: US

File Listing:

Doc. Name	File Name	Size (Bytes)	Date Produced (yyyymmdd)
us-ids	SSI04001-usldst.xml	1370	2006-07-12
us-ids	us-ids.dtd	7763	2006-07-12
us-ids	us-ids.xsl	12026	2006-07-12
package-data	SSI04001-pkda.xml	1706	2006-07-12
package-data	package-data.dtd	27025	2006-07-12
package-data	us-package-data.xsl	19263	2006-07-12
Total files size		69153	

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